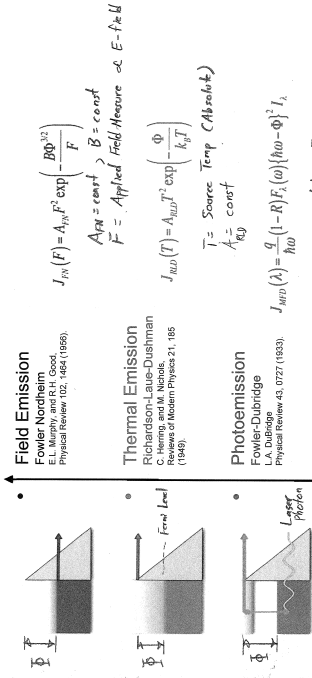


## The Canonical Emission Equations

(side courtesy of Dr. K. Jensen, Naval Research Laboratory)

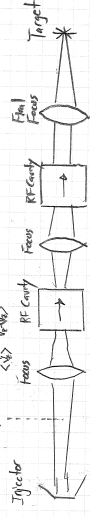


Listed chronologically

## Injectors

Ideally, want a distribution of a monoenergetic DC injector, full phase-space volume.

Low phase-space volume  $\Rightarrow$  compact beam with strong focusability.



Injectors highly important: start with a bad beam, and they're impossible to fix.

Small spreads  $\Rightarrow$  compact, cheap, and robust accelerators

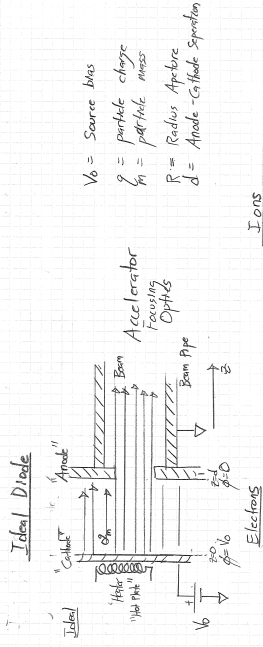
Injectors often have intricate physics

Much potential gain with improvements  
- Smaller systems, typically lower cost

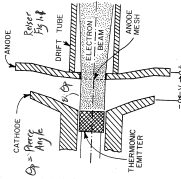
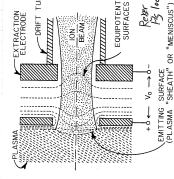
Ideal for student projects

Not easy topic, but rich and high impact.

## Injector Geometry



Ions



## Electron Emission

Thermal Emission from Maxwellian tail of Fermi-Dirac distribution of conduction electrons with current density

$$J = A T^2 e^{-W/k_B T}$$

$$A = \frac{4\pi m k_B^2}{h^3} = 1.2 \times 10^6 \frac{\text{A}}{\text{cm}^2 \text{K}^2}$$

- In lab  $A$  often  $\sim 2x$  lower than formula.
- Thermionic cathode fabrication difficult.
- Low  $W$
- Long life at high temp
- Smooth surface

Photoemitters (not covered)

Often used for short pulse  $e^-$  sources for XFEL facilities and  $e^-$  microscopes.

Field Emitters

Used on electron microscopes etc for compact bright sources.

Very Diverse Topic.

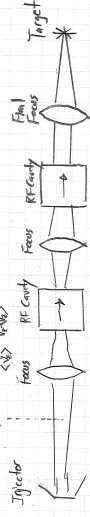
Much in re: DSTAR sources on Photoemission & High-Brightness Electron Injectors.

1

PHY 955  
Spring 2020  
Lond & Hao  
DC injectors, full

Ideally, want a distribution of a monoenergetic DC injector, full phase-space volume.

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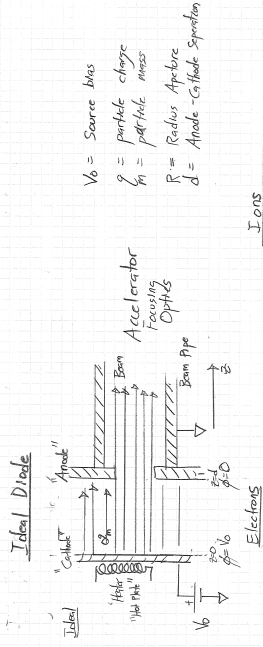
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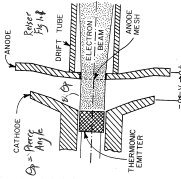
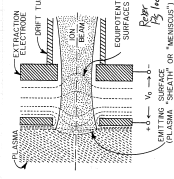
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2

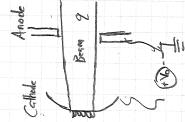
## Injector Geometry



Ions



For both electrons and ions, cannot extract arbitrary current. Will ultimately be limited by charge already emitted pushing back.



- o Particles accelerate in gap potential
- o Ex: Fixed current density  $J_z$  at emission, charge density drops with distance from emitter

Poisson's Equation

$$\frac{d^2\phi}{dz^2} = -\frac{\rho}{\epsilon_0}$$

$$E_z = -\frac{d\phi}{dz}$$

$E_z$  will push back and suppress emission.

Limiting Current: "Child-Langmuir" value.  
Analytic for steady flow:  $\partial/\partial t = 0$ .

Model ions as a cold fluid.

$$\rho(z) = \text{Density}$$

$$V(z) = \text{Flow Velocity}$$

$$\frac{\partial \rho}{\partial t} + \nabla \cdot (\rho \vec{V}) = 0$$

$$\Rightarrow \frac{\partial \rho}{\partial z} + \frac{\partial}{\partial z} (\rho V_z) = 0$$

Momentum (Non-Rel. + Coll. Fluid)

$$\rho \frac{d}{dt} (m \vec{V}) = \rho n \left( \vec{E} + \vec{V} \times \vec{B} \right) - \nabla(P)$$

Force Eqn

$$m n \frac{\partial V_z}{\partial t} + m n V_z \frac{\partial V_z}{\partial z} = \rho n E_z$$

Poisson (Electrostatic)

$$\nabla \cdot \vec{E} = \frac{\rho}{\epsilon_0}$$

$$\frac{\partial^2 \phi}{\partial z^2} = -\frac{\rho n}{\epsilon_0}$$

5/

6/

### Ion Existence

Generally more complex than electron sources.  
Many different technologies for:

- Left Ions
- Heavy Ions
- Negative Ions (H<sup>-</sup>)

often plasma is confined by a magnetic field so ions can be born "magnetized" magnetic field beam dynamics downstream.

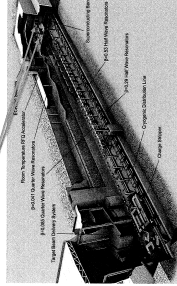
At NSCL / FRIB ECR = Electron Cyclotron Resonance Ion sources used

- Produce a spectrum of high charge state ions that must be separated downstream.

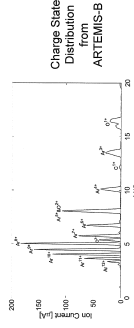
### Accelerator Facilities Use Electron Cyclotron Resonance Ion Source (ECRIS) to produce High Intensity, High Charge State Ion Beams

From B. Ishikawa

1. Produce a spectrum of high charge state ions
2. Superconducting 28 GHz VENUS based ECRIS (2020)



- Magnetic confinement and microwave heating are used to induce ionization
- GHz range microwaves ignite source plasma
- Solenoids and hexapole field confine the plasma



Michigan Science Foundation  
NSF Grant 1822781

10th International Conference on the Sources, Linacs, Other SMC 4

Want for source:  $J = \text{const} \cdot V_0^{3/2} / d^2$   
 J high  $\Rightarrow V_0$  large,  $d$  small  
 But must also suppress:  
 1) Voltage Breakdown:  $V_0 \lesssim 100 \text{ kV}$  for  $d \lesssim 1 \text{ cm}$   
 $\left(\frac{d}{1 \text{ cm}}\right)^{1/2}$  for  $d > 1 \text{ cm}$   
 Suppress to avoid distortion of hardware  
 2) Optical Aberrations: J. Kwan, LBNL  
 Nonlinear fields must be suppressed to preserve good beam quality.  
 Practical observation based with real hardware. Also check for Handbook World Press.  
 Real beam 3D not 1D. Find angled "Pierce Electrodes" can be used to keep beam approx 1D. But even with detailed code optimizations, find must  
 1mm  
 Angle kept slightly above expansion due to off-axis aberrations.  
 AT Fortran, Wiley, 1988  
 R = beam aperture radius.  
 $d \gtrsim (3 \text{ to } 4) R$

Analyse equations assuming steady  $\partial/\partial t = 0$  flow.  $\rho = n(z)e$   
 1) Continuity Equation:  $\frac{\partial}{\partial z} n V_0 + \frac{\partial}{\partial z} (n V_z) = 0 \Rightarrow \rho n V_0 = \text{const} \equiv J$   
 Note: This implies  $\rho$  goes as  $1/V_0$  is identical, but still expect very large  $n$  near cathode.  
 2) Force Equation:  $m \frac{\partial}{\partial z} \left( \frac{1}{2} m \frac{\partial V_z^2}{\partial z} + m V_0 \frac{\partial V_z}{\partial z} \right) = -e E_z = -e \frac{\partial \phi}{\partial z}$   
 $\frac{1}{2} m \frac{\partial V_z^2}{\partial z} = -e \frac{\partial \phi}{\partial z} \Rightarrow \frac{1}{2} m V_z^2 = -e \phi + C$   
 $V_z(0) = 0 \Rightarrow$  particles emitted near rest.  $\phi(0) = V_0$   
 $\frac{1}{2} m V_z^2 = e V_0 - e \phi \Rightarrow \frac{1}{2} m V_z^2 = e \phi - e V_0$   
 3) Poisson Equation:  $\frac{\partial^2 \phi}{\partial z^2} = -\frac{\rho}{\epsilon_0} = -\frac{J}{\epsilon_0 V_0}$   
 $\frac{\partial \phi}{\partial z} = -\frac{J}{\epsilon_0 V_0} z + C_1$   
 $\phi = -\frac{J}{2 \epsilon_0 V_0} z^2 + C_1 z + C_2$   
 But  $\phi(z=0) = V_0 = \phi(0) = 0$   
 $\frac{\partial \phi}{\partial z}(z=0) = -\frac{J}{\epsilon_0 V_0} \cdot 0 + C_1 = E_0(0) = 0$   
 $\Rightarrow C_1 = 0$   
 $\phi = -\frac{J}{2 \epsilon_0 V_0} z^2 + C_2$   
 $\phi(0) = V_0 \Rightarrow C_2 = V_0$   
 $\phi(z) = V_0 - \frac{J}{2 \epsilon_0 V_0} z^2$   
 Space-Charge Limited Current: do not change down cell as possible to E-field. Note: space-charge limited current is not close.  
 10/

Note that:  
 $J = \text{const} \frac{V_0^{3/2}}{d^2} \sim \begin{cases} V_0^{-1/2} \sim d^{-1/2} & d \lesssim 1 \text{ cm} \\ V_0^{-3/2} \sim d^{-5/4} & d > 1 \text{ cm} \end{cases}$   
 Current:  $I = \pi R^2 J \sim R^2 V_0^{3/2} \sim V_0^{3/2}$   
 $R \sim d$  to control aberrations.  
 $\bullet \bullet$  But  $J$  decreases as source size increases  
 $\bullet \bullet$  But  $I$  increases as source size increases  
 Also, want sources that deliver maximum current in phase-space  
 Volume measures of the beam.  
 Will find later that normalized rms x- and y-orthances measure  $\perp$  phase-space areas of the beam:  
 $\Sigma_{\text{ex}} = \langle x^2 \rangle \langle x'^2 \rangle - \langle x x' \rangle^2$   
 $\Sigma_{\text{ey}} = \langle y^2 \rangle \langle y'^2 \rangle - \langle y y' \rangle^2$   
 $\downarrow$  Phase-space  $\sim$  Envy  
 $\downarrow$  Volume

Integrate Poisson's Equation:  
 $\frac{\partial \phi}{\partial z} = -\frac{J}{\epsilon_0 V_0} z$   
 $\phi = -\frac{J}{2 \epsilon_0 V_0} z^2 + C_1 z + C_2$   
 Poisson's Equation:  $\frac{\partial^2 \phi}{\partial z^2} = -\frac{J}{\epsilon_0 V_0}$   
 Solve for J:  
 $\left(\frac{J}{\epsilon_0 V_0}\right)^{1/2} z = \left(\frac{J}{\epsilon_0}\right)^{1/2} \left(\frac{z}{V_0}\right)^{1/2}$   
 $J = \frac{2 \epsilon_0 V_0}{z} \left(\frac{z}{V_0}\right)^{1/2} \left(\frac{J}{\epsilon_0}\right)^{1/2} \frac{1}{2} V_0$   
 $J = \frac{1}{2} \epsilon_0 \left(\frac{J}{\epsilon_0}\right)^{1/2} \frac{V_0}{z}$   
 $J = \frac{1}{2} \epsilon_0 \left(\frac{J}{\epsilon_0}\right)^{1/2} \frac{V_0}{z}$   
 Also called "Child-Langmuir Law"  
 Current Density:  $J = \text{const} \frac{V_0^{3/2}}{d^2} = \text{Const} \cdot \text{Area}$   
 Current:  $I = \pi R^2 J = \frac{4 \epsilon_0 \pi R^2}{9} \left(\frac{V_0}{m}\right)^{1/2} \left(\frac{V_0}{d}\right)^{3/2} V_0^{3/2}$   
 $R = \text{Radius from Aperture}$   
 $m = m_0$   
 $z = 0$   
 $\left. \begin{aligned} &0.232 \left(\frac{R}{d}\right)^2 \left(\frac{V_0}{m}\right)^{3/2} A \\ &\text{electrons (cm}^{-2}\text{s)} \\ &5.43 \left(\frac{R}{d}\right)^2 \left(\frac{V_0}{m}\right)^{3/2} A \\ &10.15 \end{aligned} \right\}$

Beam is not converging (focusing):  $\langle x^2 \rangle = 0$

For uniform density beam in aperture:  $R = Z \langle x^2 \rangle^{1/2}$

For NR ions beam at temperature T:

$\beta \langle x^2 \rangle = \frac{1}{2} \langle \beta x^2 \rangle = \frac{1}{2} m \langle v_x^2 \rangle = \frac{1}{2} m \langle v^2 \rangle = \frac{1}{2} k_B T$

$\beta \langle x^2 \rangle = \frac{1}{2} \langle \beta x^2 \rangle = \frac{1}{2} m \langle v_x^2 \rangle = \frac{1}{2} m \langle v^2 \rangle = \frac{1}{2} k_B T$

$E_{kin} \sim \frac{1}{2} m \langle v^2 \rangle = \frac{1}{2} k_B T$

This leads naturally to a measure of source performance called "Brightness" defined as

$B = \frac{\text{Transverse}}{\text{Phase-Space Vol.}} = \frac{\text{Current}}{E_{kin} E_y} = \frac{I}{\frac{\pi R^2 \Delta v}{4} \frac{R \Delta v}{m c^2}} \propto \frac{I}{R^3 \Delta v^2}$

$B = \frac{16 \pi \epsilon_0 (e/m)^2}{9} \frac{V_0^{3/2}}{d^2 (k_B T / m c^2)}$

- Note:
- B independent of source radius R
  - Want ions as low a temp T as possible and high a voltage V\_0 as possible

$\beta \langle x^2 \rangle = \frac{1}{2} \langle \beta x^2 \rangle = \frac{1}{2} m \langle v_x^2 \rangle = \frac{1}{2} k_B T$

$\beta \langle x^2 \rangle = \frac{1}{2} \langle \beta x^2 \rangle = \frac{1}{2} m \langle v_x^2 \rangle = \frac{1}{2} k_B T$

Assume x and y plane T equal.

$J = \frac{1}{4} \epsilon_0 \left( \frac{e}{m} \right)^2 \frac{V_0^{3/2}}{d^2}$

Summary: Sources

- Well functioning sources crucial for accelerators:
  - Bright: compact phase-space  $\Leftrightarrow$  compact beam
    - smaller (more economical) structures
    - lower losses to mitigate damage
- Improving sources allows running higher intensity to get more out of accelerator
  - Upgrade accelerator
- Need also high reliability for long periods of time
  - Source not operational, then expensive machine will not work
- Sources high leverage, but also difficult:
  - Technology and physics strongly coupled
  - Rely on different material science, plasma physics, etc.
- Possible to teach a whole course on just one type of source technology.
- Many types of sources. Only scratched surface in this lecture:
 

Electrons	ions	Radioactive	Antiprotons
Thermionic emitters	hot plate (u-v)	Cathode/cool	Accel. drives source
Field Emission (point)	plasma (hydro)	discharge	capture, cool, inject
Photocathode	laser driven	beam driven	
- Source projects great for PhDs: rich physics, improvements high leverage